

**ABSTRACT****DUAL FUNCTION ARRAY FEATURE FOR CMP PROCESS CONTROL AND  
INSPECTION**

CMP process control array groups are fabricated upon the surface of the wafer for  
5 viewing through an optical microscope. The array groups include a plurality of test  
arrays, where each array includes a plurality of projecting test features. Each of the  
projecting test features are formed with the same projecting height and have a hard upper  
surface layer, such as diamond-like-carbon (DLC). All of the projecting test features  
within an array are formed with the same diameter, and the diameter of projecting test  
10 features of a particular array differs from the diameter of projecting test features in  
another array. The diameters are chosen such that the DLC surface is removed in  
specifically designed time increments, such as 5 seconds, from array to array, where  
projecting test features with the DLC surface removed appear as bright white, while the  
arrays with test features that retain some DLC surface are significantly darker.